CLAIMS

We claim:

and

1. A method for evaluating a feature, comprising:

receiving an image of the feature;

determining respective coordinates of a plurality of points on an edge of the feature in the image;

fitting a figure having a non-circular non-linear shape to the plurality of points; determining respective distances between the plurality of points and the figure;

computing a roughness parameter for the feature in response to the respective distances.

- 2. The method according to claim 1, wherein computing the roughness parameter comprises computing a contact edge roughness (CER) in response to a sum of the squares of the respective distances and a number of degrees of freedom of the figure.
- 3. The method according to claim 1, wherein computing the roughness parameter comprises computing a correlation length (CL) in response to a sum of the squares of the respective distances, a number of degrees of freedom of the figure, and an average of squares of differences of the respective distances.
- 4. The method according to claim 1, wherein computing the roughness parameter comprises performing a Fourier analysis of the respective distances, and generating a power spectrum in response to the analysis.
- 5. The method according to claim 4, wherein generating the power spectrum comprises filtering results of the Fourier analysis.
- 6. The method according to claim 5, wherein filtering the results comprises selecting a filter in response to a process used to form the feature.

7. The method according to claim 1, wherein the feature is formed on a substrate, and wherein the feature and the substrate are comprised in a semiconductor wafer.

- 8. The method according to claim 7, wherein the feature comprises a contact hole.
- 9. The method according to claim 1, wherein receiving the image comprises generating the image with a scanning electron microscope.
- 10. The method according to claim 1, wherein the figure comprises an ellipse.
- 11. The method according to claim 1, wherein the figure has a known shape.
- 12. The method according to claim 1, wherein fitting the figure comprises determining a nominal shape of the figure by averaging at least some of the plurality of the points.
- 13. The method according to claim 1, wherein the figure is selected from a closed figure and an open figure.
- 14. The method according to claim 1, wherein the distance is chosen from a perpendicular distance and a radial distance.
- 15. The method according to claim 1, wherein the feature is chosen from a reticle, a part of the reticle, and a cast of a structure.
- 16. A method for evaluating a feature, comprising:

receiving an image of the feature;

determining respective coordinates of a first plurality of points on a first edge of the feature in the image;

fitting a first figure having a first non-circular non-linear shape to the first plurality of points;

determining respective coordinates of a second plurality of points on a second edge of the feature in the image;

fitting a second figure having a second non-circular non-linear shape to the second plurality of points;

determining respective distances between the first and the second figures; and computing a roughness parameter for the feature in response to the respective distances.

17. Apparatus for evaluating a feature, comprising:

an imaging unit which is adapted to generate an image including the feature; and a processor which is adapted to:

determine respective coordinates of a plurality of points on an edge of the feature in the image,

fit a figure having a non-circular non-linear shape to the plurality of points,

determine respective distances between the plurality of points and the figure, and
compute a roughness parameter for the feature in response to the respective
distances.

- 18. The apparatus according to claim 17, wherein computing the roughness parameter comprises computing a contact edge roughness (CER) in response to a sum of the squares of the respective distances and a number of degrees of freedom of the figure.
- 19. The apparatus according to claim 17, wherein computing the roughness parameter comprises computing a correlation length (CL) in response to a sum of the squares of the respective distances, a number of degrees of freedom of the figure, and an average of squares of differences of the respective distances.
- 20. The apparatus according to claim 17, wherein computing the roughness parameter comprises performing a Fourier analysis of the respective distances, and wherein the processor is adapted to generate a power spectrum in response to the analysis.

21. The apparatus according to claim 20, wherein generating the power spectrum comprises filtering results of the Fourier analysis.

- 22. The apparatus according to claim 21, wherein filtering the results comprises selecting a filter in response to a process used to form the feature.
- 23. The apparatus according to claim 17, wherein the feature is formed on a substrate and wherein the substrate and the feature are comprised in a semiconductor wafer.
- 24. The apparatus according to claim 23, wherein the feature comprises a contact hole.
- 25. The apparatus according to claim 17, wherein the imaging unit and the processor are comprised in a scanning electron microscope.
- 26. The apparatus according to claim 17, wherein the figure comprises an ellipse.
- 27. The apparatus according to claim 17, wherein the figure has a known shape.
- 28. The apparatus according to claim 17, wherein the processor is adapted to determine a nominal shape of the figure by averaging at least some of the plurality of the points.
- 29. The apparatus according to claim 17, wherein the figure is selected from a closed figure and an open figure.
- 30. The apparatus according to claim 17, wherein the distance is chosen from a perpendicular distance and a radial distance.
- 31. The apparatus according to claim 17, wherein the feature is chosen from a reticle, a part of the reticle, and a cast of a structure.
- 32. Apparatus for evaluating a feature, comprising: an imaging unit which is adapted to generate an image including the feature; and

a processor which is adapted to:

determine respective coordinates of a first plurality of points on a first edge of the feature in the image,

fit a first figure having a first non-circular non-linear shape to the first plurality of points,

determine respective coordinates of a second plurality of points on a second edge of the feature in the image,

fit a second figure having a second non-circular non-linear shape to the second plurality of points,

determine respective distances between the first and the second figures, and compute a roughness parameter for the feature in response to the respective distances.

33. A method for evaluating a feature, comprising:

receiving an image of the feature;

determining respective coordinates of a plurality of points on an edge of the feature in the image;

fitting a figure to the plurality of points;

determining respective distances between the plurality of points and the figure; and

computing a correlation length in response to a sum of the squares of the respective distances, a number of degrees of freedom of the figure, and an average of squares of differences of the respective distances.

34. A method for evaluating a feature, comprising:

receiving an image of the feature;

determining respective coordinates of a plurality of points on an edge of the feature in the image;

fitting a figure to the plurality of points;

determining respective distances between the plurality of points and the figure;

performing a Fourier analysis of the respective distances; and filtering results of the Fourier analysis in response to a process used to form the

35. A method for evaluating a feature, comprising:

receiving an image of the feature;

feature.

determining respective coordinates of a plurality of points on an edge of the feature in the image;

fitting a figure to the plurality of points;

determining respective distances between the plurality of points and the figure; performing a Fourier analysis of the respective distances; and filtering results of the Fourier analysis in response to a shape of the feature.

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36. Apparatus for evaluating a feature, comprising:

an imaging unit which is adapted to generate an image including the feature; and a processor which is adapted to:

determine respective coordinates of a plurality of points on an edge of the feature in the image,

fit a figure to the plurality of points,

determine respective distances between the plurality of points and the figure, and compute a correlation length in response to a sum of the squares of the respective distances, a number of degrees of freedom of the figure, and an average of squares of differences of the respective distances.

37. Apparatus for evaluating a feature, comprising:

an imaging unit which is adapted to generate an image including the feature; and a processor which is adapted to:

determine respective coordinates of a plurality of points on an edge of the feature in the image,

fit a figure to the plurality of points,

determine respective distances between the plurality of points and the figure,

perform a Fourier analysis of the respective distances, and filter results of the Fourier analysis in response to a process used to form the

38. Apparatus for evaluating a feature, comprising:

feature.

an imaging unit which is adapted to generate an image including the feature; and a processor which is adapted to:

determine respective coordinates of a plurality of points on an edge of the feature in the image,

fit a figure to the plurality of points,
determine respective distances between the plurality of points and the figure,
perform a Fourier analysis of the respective distances, and
filter results of the Fourier analysis in response to a shape of the feature.